



SEN 09/834,751

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Sergey A. Velichko et al.

Examiner: Craig Steven Miller

Serial No.: 09/834,751

Group Art Unit: 2857

Filed: April 13, 2001

Docket No.: 303.750US1

Title: CONCURRENT CONTROL OF SEMICONDUCTOR PARAMETRIC
TESTING

RESPONSE UNDER 37 CFR § 1.111

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

This response is accompanied by a Petition, as well as the appropriate fee, to obtain a one-month extension of the period for responding to the Office Action, thereby moving the deadline for response from August 19, 2005 to September 19, 2005.

REMARKS

This responds to the Office Action mailed on May 19, 2005, and the references cited therewith.

No claims are cancelled, amended, or added; as a result, claims 1-58 remain pending in this application.

§103 Rejection of the Claims

Claims 1-58 were rejected under 35 U.S.C. § 103(a) as being unpatentable over Ekstedt et al. (U.S. Patent No. 5,206,582) in view of Tong (U.S. Patent No. 4,896,269) and Yun (U.S. Patent No. 6,240,331).

Ekstedt describes a control system for automated parametric test equipment, including the ability to define and execute test sequences on such equipment. Ekstedt further teaches, as in the cited Figure 9's element 76, sequential control of both semiconductor test equipment such as a wafer loader, and parametric test equipment such as a prober.

Tong teaches prioritization of scheduling conflicting jobs, and fails to address concurrency but simply addresses prioritization of jobs or tasks that are not concurrent but are performed serially.